

2878

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Application No.: 09/639,495 Confirmation No.: Unknown
First Named Inventor: Mehrdad Nikoonahad Filing Date: August 14, 2000
Group Art Unit: 2878 Examiner: Unknown
Atty. Docket No.: TNCR.181US0
Title: METROLOGY SYSTEM USING OPTICAL PHASE
Assignee: KLA-TENCOR CORPORATION

#8
4/14/03
[Signature]

San Francisco, California
March 5, 2003

COMMISSIONER FOR PATENTS
Washington, D. C. 20231

RECEIVED
APR - 9 2003
TECHNOLOGY CENTER 2800

**SUPPLEMENTAL
INFORMATION DISCLOSURE STATEMENT**

Dear Sir:

Pursuant to 37 C.F.R. §§ 1.56, 1.97, and 1.98, Applicants call the documents listed on the enclosed Form PTO-1449 to the Examiner's attention in this patent application.

☒ Copies of the documents listed on the accompanying Form PTO-1449 are enclosed.

Citation of these documents shall not be construed as (1) an admission that the documents are prior art with respect to the invention or inventions claimed in this application, (2) a representation that a search has been made (other than as indicated by any cited document), or (3) an admission that the cited information is, or is considered to be, material to patentability as defined in § 1.56(b).

This information disclosure statement is submitted under 37 C.F.R. § 1.97(b) and consequently no fee should be required.

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on March 31, 2003.

Valerie Olsen

Valerie Olsen

3/31/03

Date of Signature

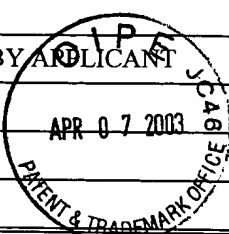
Respectfully submitted,

James S. Hsue

Reg. No. 29,545

Attorney for Applicant(s)

| | | | | | | | |
|--|--|--|--|----------------------------|--|------------------|--|
| U.S. Department of Commerce, Patent and Trademark Office | | | | Atty Dock No. | | Application No. | |
| | | | | TNCR.181US0 | | 09/639,495 | |
| INFORMATION DISCLOSURE STATEMENT BY APPLICANT | | | | Applicant(s) | | Confirmation No. | |
| (Use several sheets if necessary) | | | | Mehrdad Nikoonahad, et al. | | Unknown | |
| | | | | Filing Date | | Group | |
| | | | | August 14, 2000 | | 2878 | |



| U.S. Patent Documents | | | | | | | |
|-----------------------|----|-----------------|------|------|-------|----------|----------------------------|
| *Examiner Initial | | Document Number | Date | Name | Class | Subclass | Filing Date If Appropriate |
| | AA | | | | | | |
| | AB | | | | | | |
| | AD | | | | | | |
| | AE | | | | | | |
| | AF | | | | | | |
| | AG | | | | | | |
| | AI | | | | | | |
| | AJ | | | | | | |
| | AD | | | | | | |
| | AE | | | | | | |
| | AF | | | | | | |
| | AG | | | | | | |
| | AK | | | | | | |
| | AD | | | | | | |
| | AE | | | | | | |
| | AG | | | | | | |
| | AH | | | | | | |
| | AI | | | | | | |

| Foreign Patent Documents | | | | | | | | |
|--------------------------|----|----------|------|---------|-------|----------|-------------|----|
| | | | | | | | Translation | |
| | | Document | Date | Country | Class | Subclass | Yes | No |
| | AL | | | | | | | |
| | AM | | | | | | | |

| OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.) | | |
|--|----|---|
| | AQ | R. Pforr, et al., "In-Process Image Detecting Technique For Determination Of Overlay, And Image Quality For ASM-L Wafer Stepper", <i>SPIE Vol. 1674 Optical/Laser Microlithography V</i> (1992) pp. 594-608 |

| | |
|----------|-----------------|
| Examiner | Date Considered |
|----------|-----------------|

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.